

Olympus 50X WLI Objective

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Product Downloads

General

Model Number:
WLI50XMRTC

Compatible Tube Lens Focal Length (mm):
Focal Length: 180mm

Type:
Microscope Objective

Style:
InfinityCorrected

Manufacturer:

Olympus

Note:

Designed to be used with a 180mm Tube Lens,
Sold Separately

Physical & Mechanical Properties

0.44 **Field of View (mm):**

44.00 **Length excluding Threads (mm):**

31.5 **Maximum Diameter (mm):**

Optical Properties

3.60 **Focal Length FL (mm):**

50X **Magnification:**

0.80 **Numerical Aperture NA:**

0.42 **Resolving Power (μm):**

0.43 **Depth of Field (μm):**

1 **Working Distance (mm):**

22 **Field Number (mm):**

45 **Parfocal Length (mm):**

1074.2 **Depth of Focus (μm):**

5.76 **Entrance Pupil Diameter (mm):**

Threading & Mounting

RMS / 20.32mm x 36 TPI **Mounting Threads:**

Regulatory Compliance

[Exempt](#) **RoHS 2015:**

[View](#) **Certificate of Conformance:**

Product Details

- Combines High Numerical Aperture and Broad Field of View
- Thermal Compensation & Stability Features
- Suitable for 3D Surface Metrology and Profilometry

Olympus WLI Infinity Corrected Interferometry Objectives' advanced optical design combines a high numerical aperture with a broad field of view, capturing fine surface details across large areas for visual clarity. Each objective features a built-in adjustment ring that compensates for temperature-induced focused shifts, allowing stability and consistent measurement accuracy even under unstable environmental conditions. These objectives are designed to be used with a 180mm focal length tube lens and are available in magnification of 10 – 50X. Olympus WLI Infinity Corrected Interferometry Objectives are ideal for 3D surface metrology and profilometry applications, including semiconductor inspection, precision machining, optical coating evaluation, and microelectronic characterization.